

FIG.1(PRIOR ART)

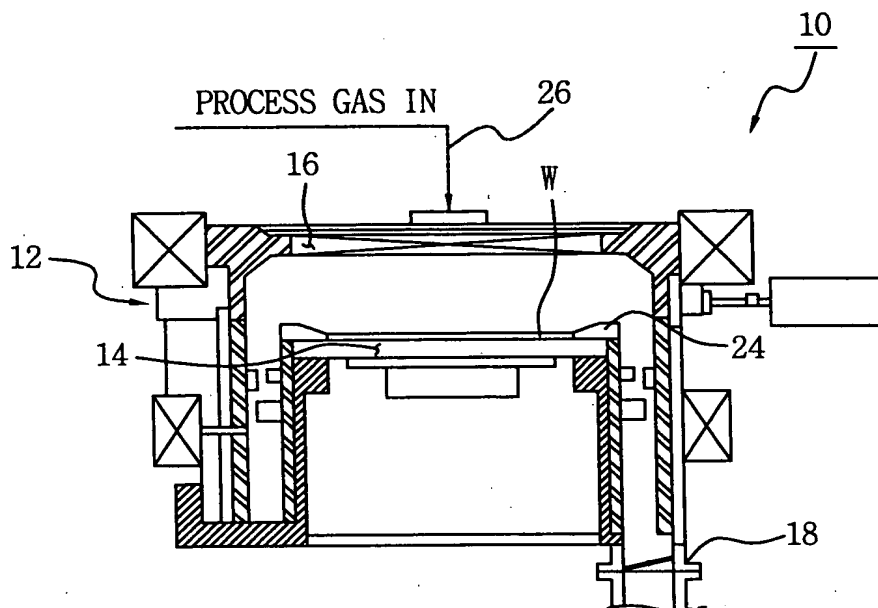


FIG.2(PRIOR ART)

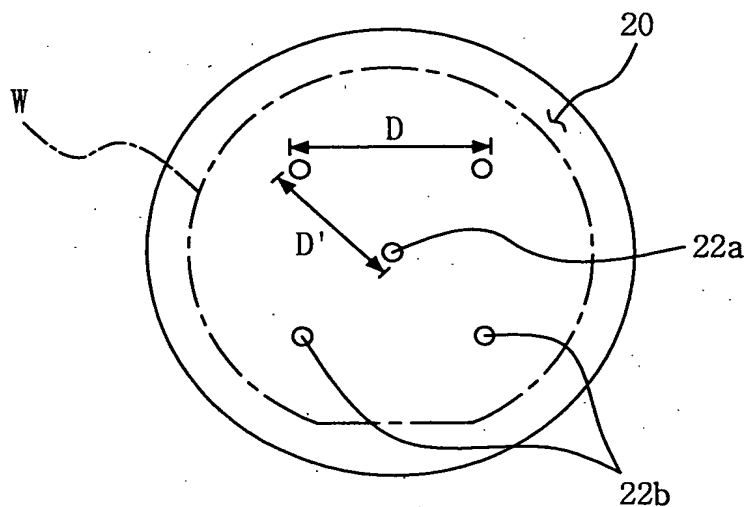


FIG.3(PRIOR ART)

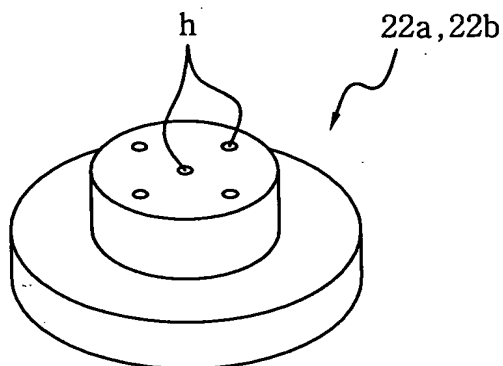


FIG.4(PRIOR ART)

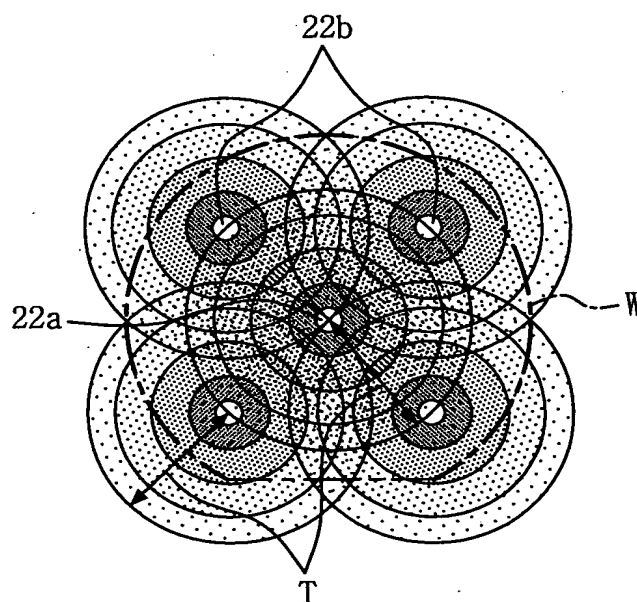


FIG.5(PRIOR ART)

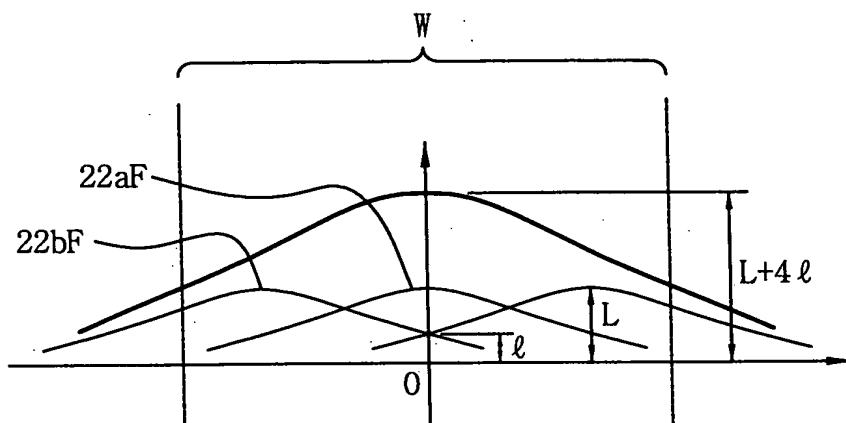


FIG.6(PRIOR ART)

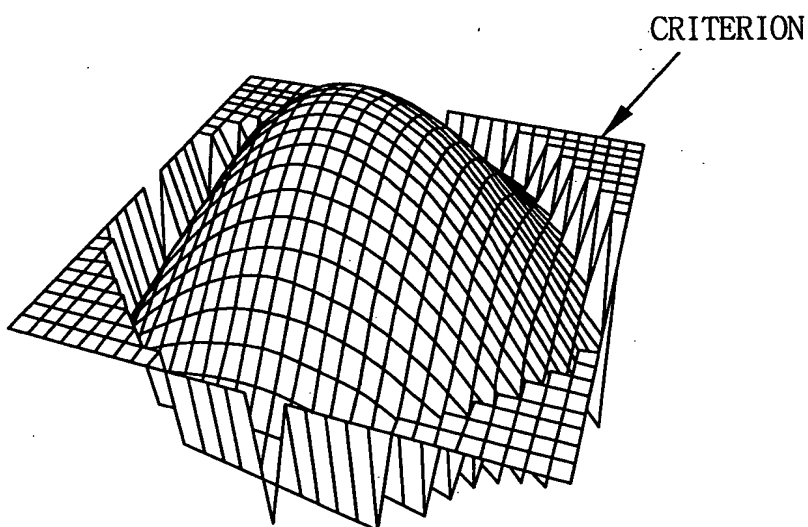


FIG.7a(PRIOR ART)

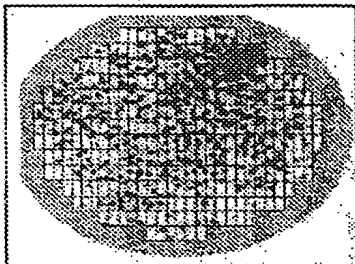


FIG.7b(PRIOR ART)

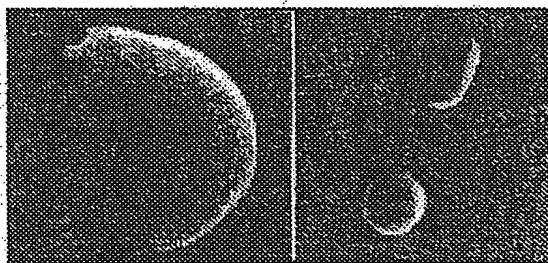


FIG.7c(PRIOR ART)



FIG.8(PRIOR ART)

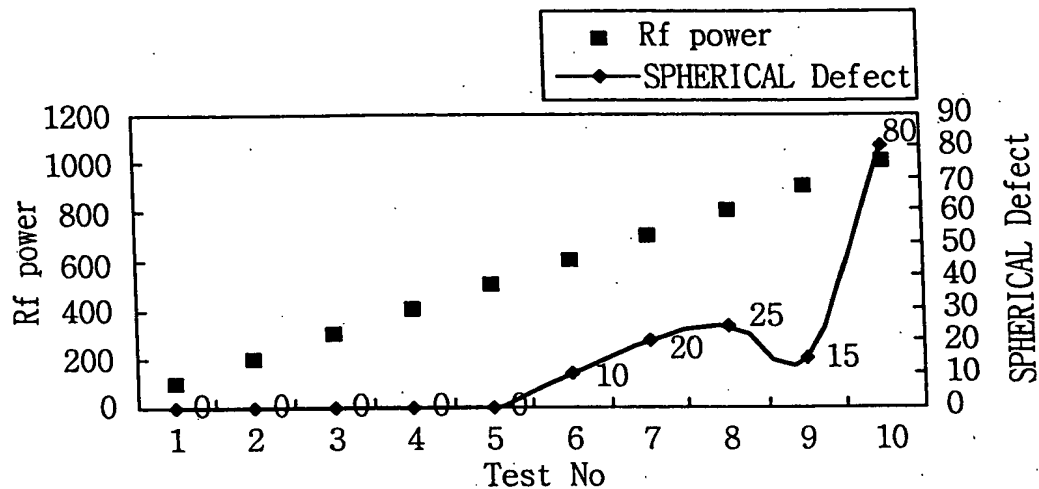
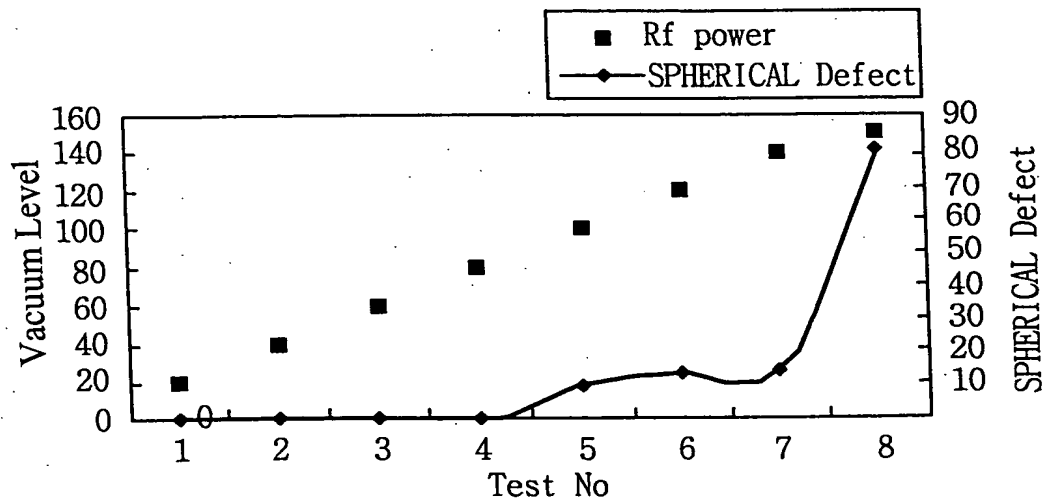


FIG.9(PRIOR ART)



APPARATUS AND SYSTEM FOR, AND METHOD OF SUPPLYING PROCESS GAS IN
SEMICONDUCTOR DEVICE MANUFACTURING EQUIPMENT

Application No. NEW - Attorney Docket No. SEC.1140

Inventors: Sung-Sok CHOI et al.

FIG. 10(PRIOR ART)

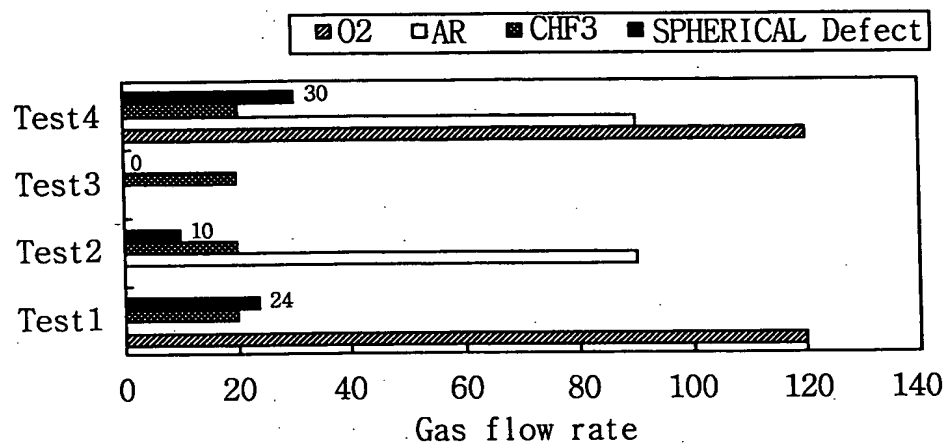


FIG. 11a

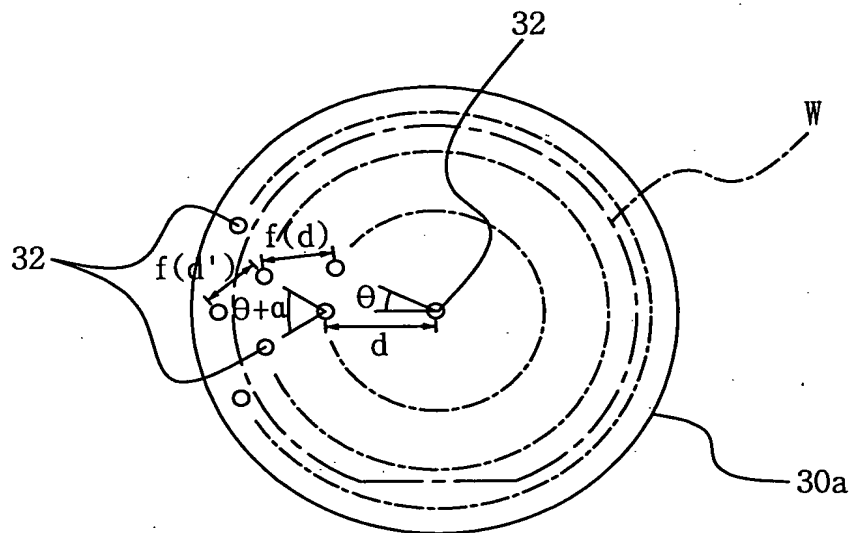
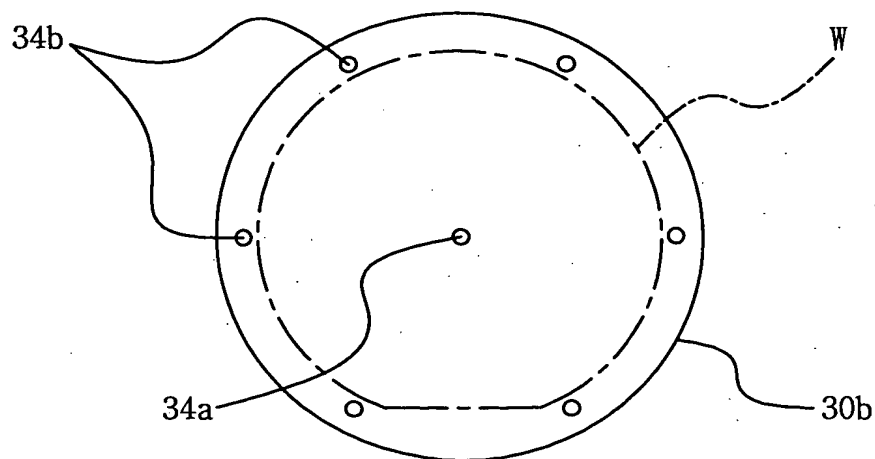


FIG. 11b



APPARATUS AND SYSTEM FOR, AND METHOD OF SUPPLYING PROCESS GAS IN
SEMICONDUCTOR DEVICE MANUFACTURING EQUIPMENT

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Inventors: Sung-Sok CHOI et al.

FIG. 12a

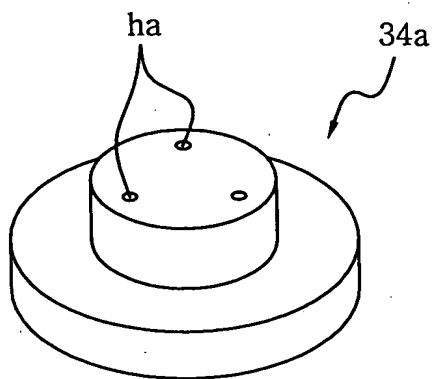
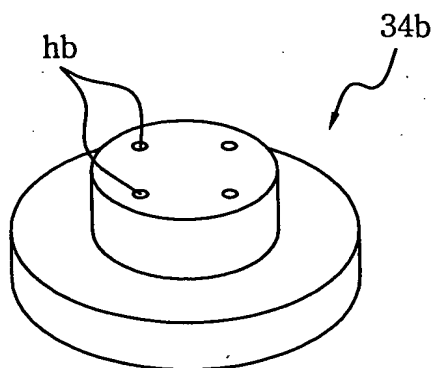


FIG. 12b



APPARATUS AND SYSTEM FOR, AND METHOD OF SUPPLYING PROCESS GAS IN
SEMICONDUCTOR DEVICE MANUFACTURING EQUIPMENT

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Inventors: Sung-Sok CHOI et al.

FIG. 13

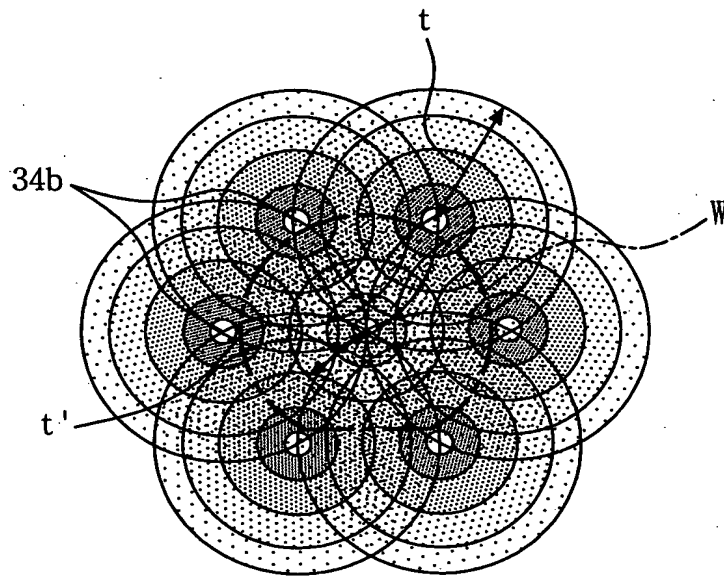


FIG. 14

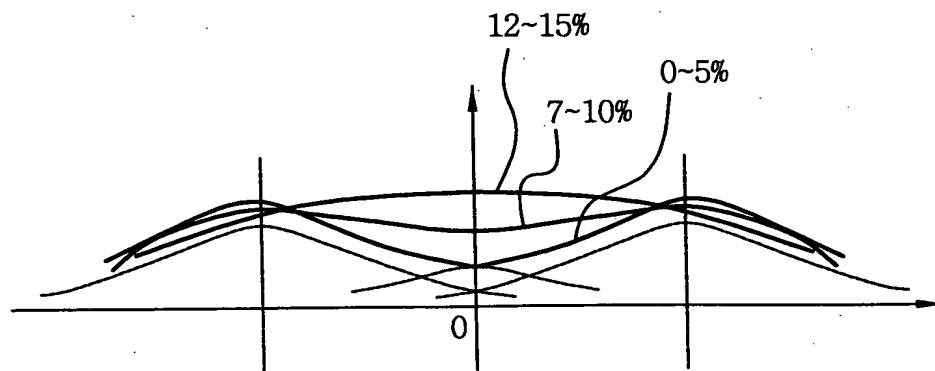


FIG. 15

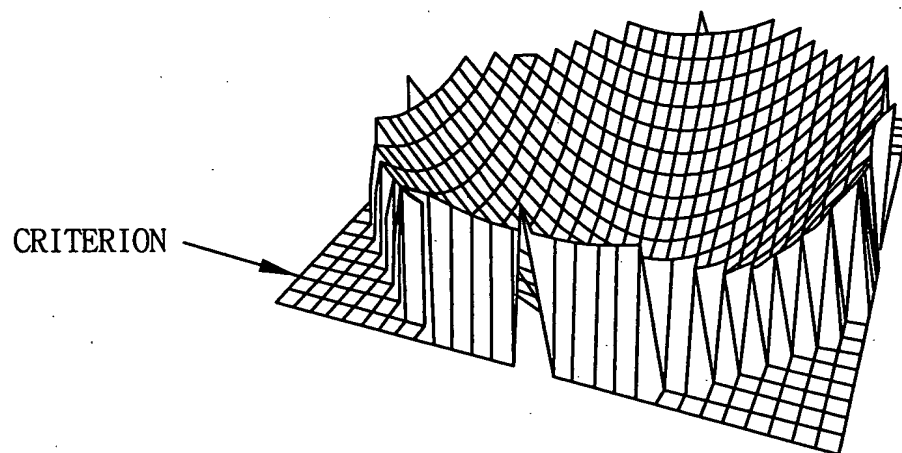


FIG. 16

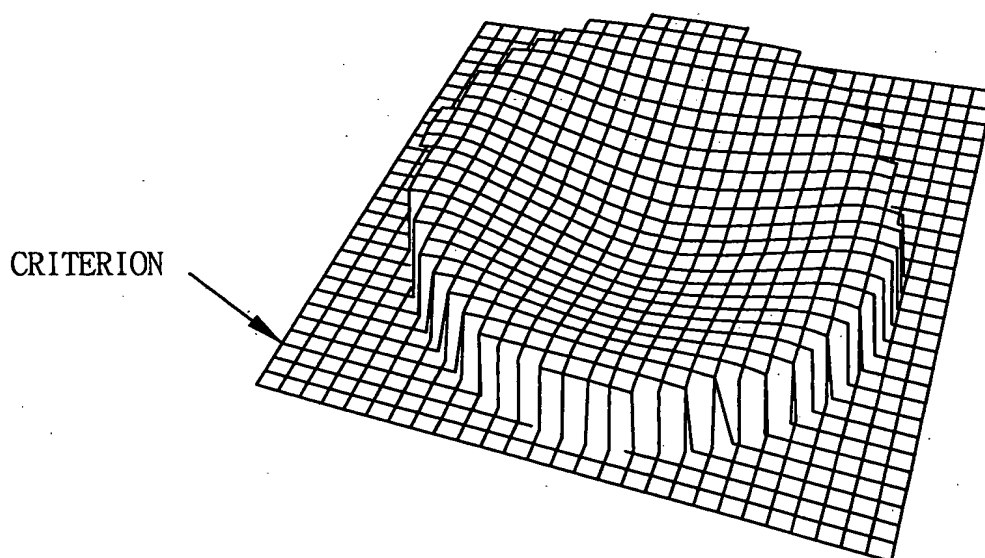


FIG. 17

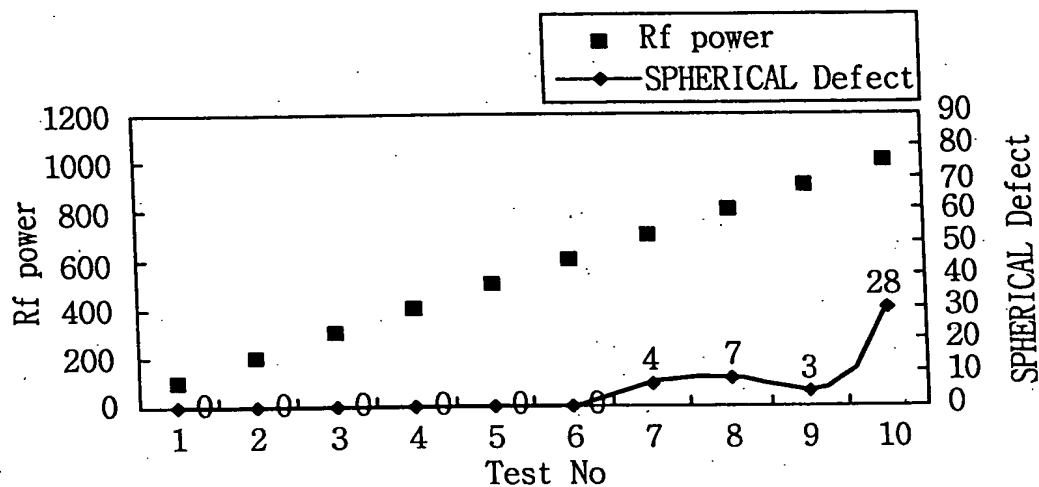
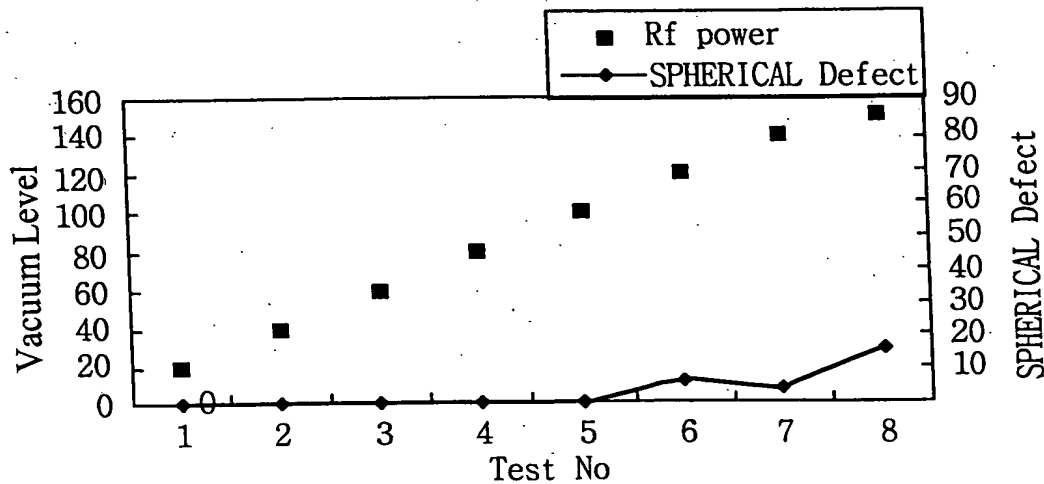


FIG. 18



APPARATUS AND SYSTEM FOR, AND METHOD OF SUPPLYING PROCESS GAS IN
SEMICONDUCTOR DEVICE MANUFACTURING EQUIPMENT

Application No. NEW - Attorney Docket No. SEC.1140

Inventors: Sung-Sok CHOI et al.

FIG. 19

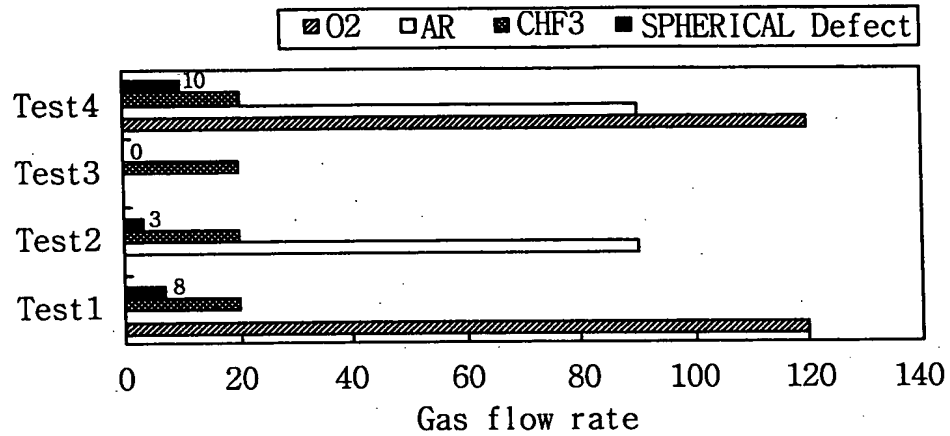
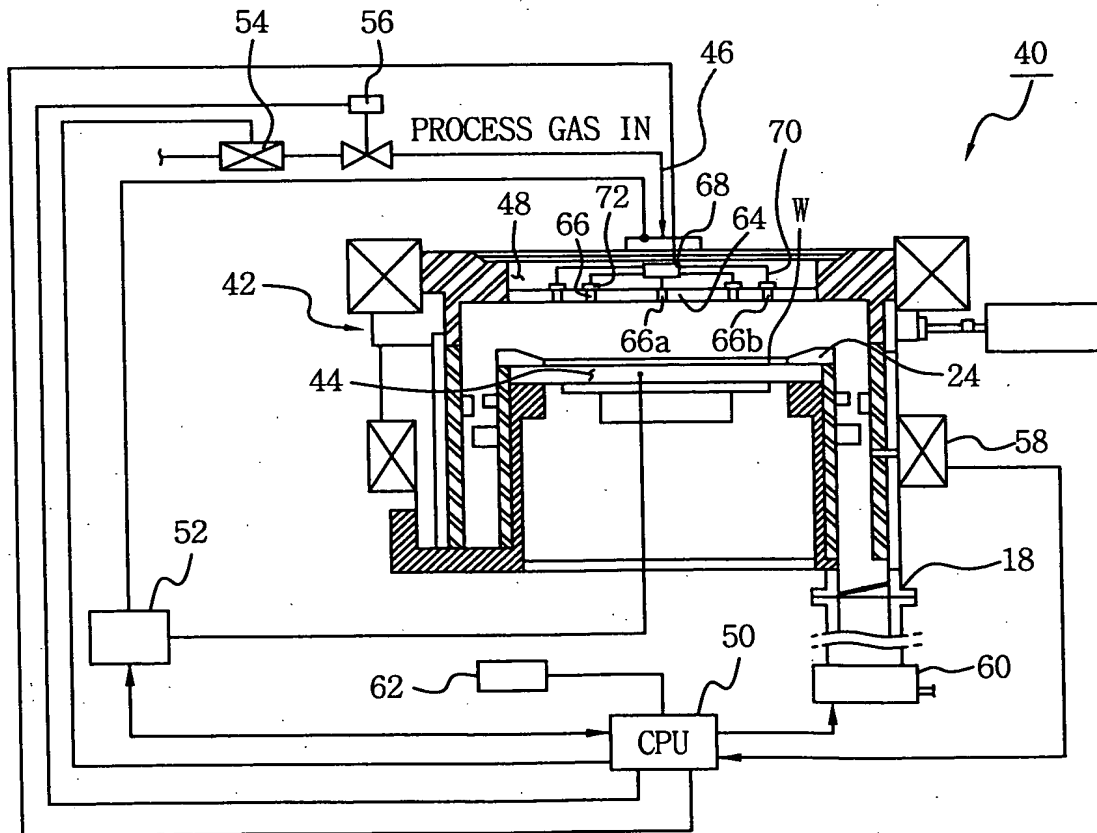


FIG. 20



APPARATUS AND SYSTEM FOR, AND METHOD OF SUPPLYING PROCESS GAS IN
SEMICONDUCTOR DEVICE MANUFACTURING EQUIPMENT

Application No. NEW - Attorney Docket No. SEC.1140

Inventors: Sung-Sok CHOI et al.

FIG. 21

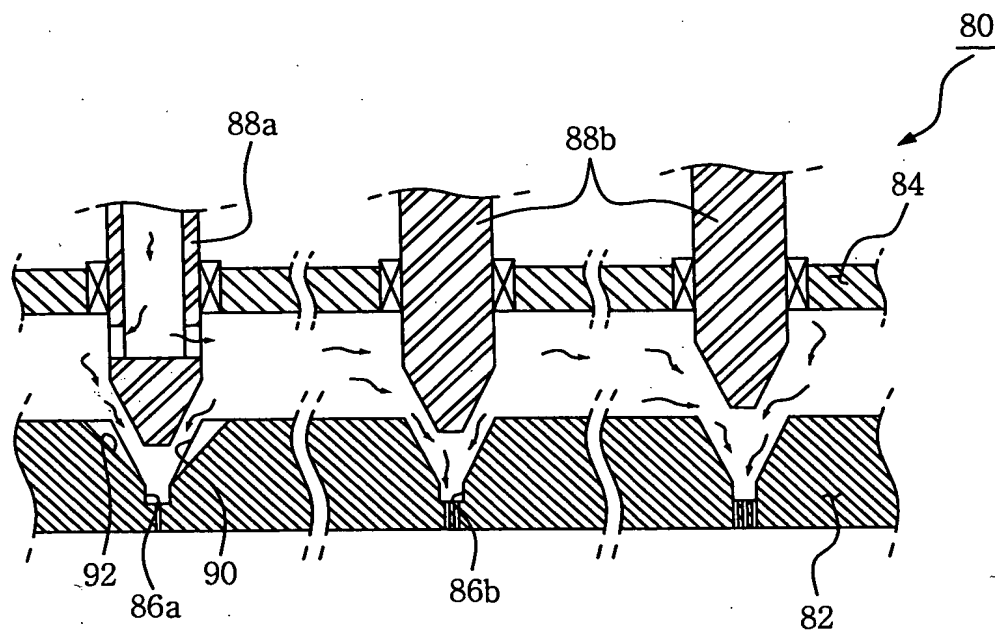


FIG. 22

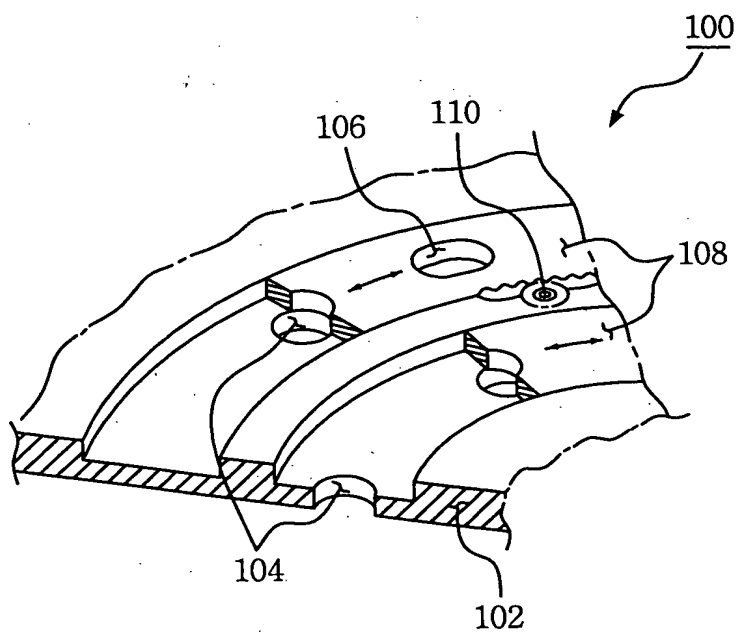


FIG. 23

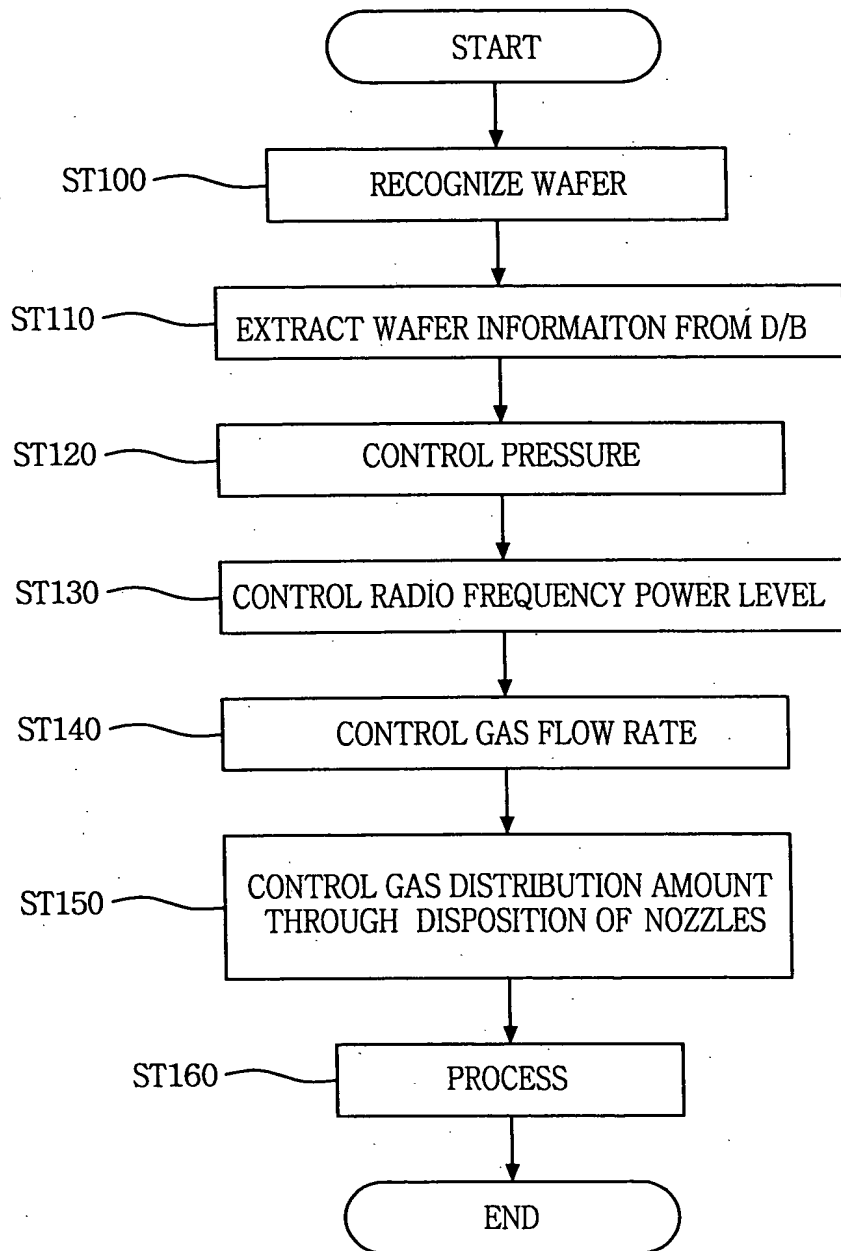


FIG. 24

